



PATENT

Attv. Dkt. No. AMAT/5999.Y1/CMP/CMP/RKK

In re Application of:
Moon, et al.

Serial No.: 10/025,144

Confirmation No.: 5051

Filed: December 18, 2001

**For: Method and Apparatus for
Polishing Metal and Dielectric
Substrates**

MAIL STOP NON-FEE AMENDMENT
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

Group Art Unit: 2813

Examiner: Stephen W. Smoot

CERTIFICATE OF MAILING

37 CFR 1.8

I hereby certify that this correspondence is being deposited on April 7, 2004 with the United States Postal Service as First Class Mail in an envelope addressed to: Mail Stop Non-Fee Amendment, Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

April 7, 2004
Date

Signature

RESPONSE TO OFFICE ACTION DATED JANUARY 7, 2004

In response to the Office Action dated January 7, 2004, having a shortened statutory period for response set to expire on April 7, 2004, please enter this response and reconsider the claims pending in the application for reasons discussed below. Although Applicant believes that no additional fees are due in connection with this response, the Commissioner is hereby authorized to charge counsel's Deposit Account No. 20-0782/5999.Y1/KMT, for any fees, including extension of time fees or excess claim fees, required to make this response timely and acceptable to the Office.

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper. **Remarks** begin on page 10 of this paper.